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Brendy Belony

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**Attorney Docket No.: NECF 17.638B**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Inventor: Mami MIYASAKA

Serial No.:

Filed:

Title: **ELECTRON BEAM EXPOSURE MASK, ELECTRON BEAM EXPOSURE METHOD, METHOD OF FABRICATING SEMICONDUCTOR, AND ELECTRON BEAM EXPOSURE APPARATUS**

Examiner:

Group Art Unit:

Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

**PRELIMINARY AMENDMENT**

S I R :

Prior to examination on the merits and prior to calculation of the filing fee, please amend the above-captioned application as follows: